

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:)	
Shinichiro Nohdo)	Group Art Unit: 2877
Application No. 10/812,602)	Confirmation No.: 3173
Filed: March 30, 2004)	
For: WAFER, EXPOSURE MASK, METHOD OF)	Examiner: Rebecca Slomski
DETECTING MARK AND METHOD OF)	
EXPOSURE)	

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

RESPONSE TO APRIL 24, 2007 OFFICE ACTION

Dear Sir:

This Amendment is submitted in response to the Office Action mailed April 24, 2007. Applicant respectfully requests reconsideration of the application in view of this amendment and remarks herein.